



App No. 09/360,292

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 09/360,292  
Filing Date ..... July 22, 1999  
Inventor..... Sujit Sharan et al.  
Assignee..... Micron Technology, Inc.  
Group Art Unit..... 1765  
Examiner ..... Ahmed, Shamim  
Attorney's Docket No. .... MI22-1106  
Title: Plasma Etching Process

**RESPONSE TO MARCH 15, 2004 OFFICE ACTION**

To: Mail Stop Amendment  
Commissioner for Patents  
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Alexandria, VA 22313-1450

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**AMENDMENTS**

**Introductory Comments**

In response to the Office Action dated March 15, 2004, applicant remarks as follows.